

Code No: **R41035**

R10

Set No. 1

IV B.Tech I Semester Regular/Supplementary Examinations, Nov/Dec - 2015

MICRO ELECTRO MECHANICAL SYSTEMS

(Open Elective)

Time: 3 hours

Max. Marks: 75

**Answer any FIVE Questions
All Questions carry equal marks**

- 1 a) With the help of suitable diagram explain etching process. [5]
b) What is lithography? With the help of suitable diagrams explain various lithographic techniques. [10]
- 2 a) Explain the various sensing mechanisms in detail. [10]
b) What factors are affecting flow and pressure measurement by micro phone? [5]
- 3 a) How do thermally activated MEMS relay works? [9]
b) Elucidate the basics of heat transfer process. [6]
- 4 a) Is beam splitter a light modulator? Discuss the reasons. [7]
b) Define the terms: i) Reflection ii) Refraction
iii) Interference iv) Polarization [8]
- 5 a) With suitable diagram, explain the principle of operation of magneto resistive sensor. [10]
b) State the applications of Magnetic MEMS actuators [5]
- 6 a) Write short notes on cantilever resonators. [8]
b) Give exclusive applications of phase shifter. [7]
- 7 a) Draw a schematic diagram of a diaphragm based micro pump. [8]
b) Discuss the applications of micro fluidic systems. [7]
- 8 a) Explain the principle of operation of mass-sensitive chemo sensor [8]
b) Write short notes on e-nose. [7]

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Set No. 2

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Time: 3 hours

Max. Marks: 75

**Answer any FIVE Questions
All Questions carry equal marks**

- 1 a) Describe various steps in surface micro machining with neat sketches. [7]
b) Describe various steps in LIGA process with a neat block diagram. [8]
- 2 List out various actuation methods used in MEMS. Describe the principles of any two methods with neat sketches. [15]
- 3 a) What is the function of MEMS thermo vessel chip? What are the basic design requirements of most of micro thermo vessels? [8]
b) Write short notes on data storage cantilever. [7]
- 4 a) How many types of MEMS micro lens do you know? Explain their design features. [8]
b) Write short notes on micro mirror. [7]
- 5 Comprehensively discuss the principle of operation of magnetic probe based storage device. [15]
- 6 a) What is an inductor? What types of MEMS inductors do you know [7]
b) Describe the principle and operation of radio frequency MEM systems. [8]
- 7 With the suitable diagrams, explain the principles of following:
(i) Dielectro phoresis
(ii) Opto electro wetting [15]
- 8 Write short notes on following:
(i) fluorescence detection
(ii) Sensing mechanism
(iii) Calorimetric spectroscopy. [15]

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Set No. 3

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MICRO ELECTRO MECHANICAL SYSTEMS

(Open Elective)

Time: 3 hours

Max. Marks: 75

**Answer any FIVE Questions
All Questions carry equal marks**

- 1 a) Explain various deposition methods used in micro fabrication and explain any one. [8]
b) Define and discuss the diffusion process used in MEMS industry. [7]
- 2 a) With suitable diagram, describe in detail the principle of Inchworm Technology. [8]
b) List out the physical parameters that can be sensed by using sensory devices [7]
- 3 Write short notes on following;
(i) Thermistors
(ii) Thermo Devices
(iii) Thermo couple and Thermo pile [15]
- 4 a) What is wave guide? Show different types of wave guides. [8]
b) Discuss the applications of MOEMS devices. [7]
- 5 Discuss the principle of operation and construction of a typical micro plate type MEMS magnetic sensor. [15]
- 6 a) What is varactor? List the advantages of MEMS varactor over the traditional varactor. [7]
b) Mention some of the design scenarios of RF MEMS you know. [8]
- 7 a) What are three important parameters, which are considered while designing the micro fluidic systems? [8]
b) What are the kinds of fluid actuation methods? Explain any one. [7]
- 8 a) Write down the principle of operation of a simple biochemical sensor. [8]
b) Write short notes on chemotransistors. [7]

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Set No. 4

IV B.Tech I Semester Regular/Supplementary Examinations, Nov/Dec - 2015

MICRO ELECTRO MECHANICAL SYSTEMS

(Open Elective)

Time: 3 hours

Max. Marks: 75

**Answer any FIVE Questions
All Questions carry equal marks**

- 1 a) Give a history of MEMS manufacturing process. [7]
b) Discuss in brief structural and sacrificial materials with their examples. [8]
- 2 a) How does MEMS gyroscope works. [10]
b) What do you meant by piezoelectricity? [5]
- 3 a) Write short notes on micro plate type gas sensor. [8]
b) Discuss the principle of peltier effect heat pump. [7]
- 4 Explain the principle of operation of various types of optical switches used in optical communication systems. [15]
- 5 a) Distinguish between magneto transistors and magnetic diodes. [7]
b) State and explain any one type of magnetic actuator with neat sketch. [8]
- 6 a) Briefly discuss about resonator and filter. [8]
b) What are the limitations and advantages of radio frequency MEMS based communication systems? [7]
- 7 Write short notes on the following:
(i) Electro osmosis flow
(ii) electro thermal flow
(iii) Micro fluid dispenser [15]
- 8 a) With suitable schematic diagram, explain the principle and operation of chemocapacitor. [10]
b) What do you meant by chem.-lab-on-a-chip (CLOC)? [5]